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## INFORMATEON SISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional) TWI-12030	Application Number 10/658,176		
Applicant(s)			
Jon Opsal et al.			
Filing Date	Group Art Unit		
Sentember 9 2003	2877		

## **U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	Ref	DOCUMENT NUMBER	DATE	Name	CLASS	SUBCLASS	FILING DATE
RAYL	*AA	5,880,838	03/09/1999	Marx et al.	356	351	06/05/1996

## FOREIGN PATENT DOCUMENTS

	·	DOCUMENT					TRANSLATION	
REF	Number	DATE	COUNTRY	CLASS	SUBCLASS	YES	No	
·	1							
		<del></del>					1	

## **OTHER DOCUMENTS**

(Including Author, Title, Date, Pertinent Pages, Etc.)

PAR	AB	Xu Wang et al., "Measuring and modeling optical diffraction from subwavelength features", J. Opt. Soc. Am. A, Vol. 18, No. 3, March 2001, pp. 565-572.
Pap	AC	D.S. Marx et al., "Optical diffraction of focused spots and subwavelength structures", J. Opt. Soc. Am. A, Vol. 14, No. 6, June 1997, pp. 1268-1278.
Rn	AD	D.S. Marx et al., "Polarization quadrature measurement of subwavelength diffracting structures", Applied Optics, Vol. 36, No. 25, September 1, 1997, pp. 6434-6440.
pn	AE	J. Opsal et al., "Effects of feature edges on thickness readings of thin oxides", SPIE Vol. 1594, Process Module Metrology, Control and Clustering, 1991, pp. 313-321.

Examiner Date Considered 8/6/04

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.